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Nota di contenuto	Intro -- Scientific Advisory Committee -- Organizing Committee -- Preface -- Contents -- Free Vibration of Compliant Mechanisms Based on Euler-Bernoulli-Beams -- 1 Introduction -- 2 Analytical Method -- 2.1 Differential Equations of Motion -- 2.2 Boundary Conditions -- 2.3 Continuity Conditions -- 2.4 Matrix Form -- 2.5 Transfer Matrices -- 2.6 Equation of the Natural Frequencies -- 2.7 First Verification of the Analytical Approach -- 3 Design of the Calculation Tool -- 3.1 Programming Language Python -- 3.2 Design of the Graphical User Interface for the Calculation Tool -- 4 Validation and Verification -- 4.1 Test Specimen Design -- 4.2 Material Choice and Manufacturing -- 4.3 Free Vibration Testing -- 4.4 Dynamic Vibration Testing -- 4.5 Verification Through Finite Element Analysis -- 5 Results -- 6 Discussion -- 7 Conclusion and Outlook -- 8 Appendix -- References -- Towards Topology Optimization of Pressure-Driven Soft Robots -- 1 Introduction -- 2 Pressure Load Modeling -- 3 Topology Optimization Formulation -- 4 Numerical Results and Discussions -- 5 Closure -- References -- Compliant Finger Gripper Based on Topology Optimization -- 1 Introduction -- 2 Related Work -- 3 Motivation and Organization -- 4 Formulation of the Problem, Objective and Constraints -- 5 Contact Modeling in Large Deformation Between Beams and External Surfaces -- 6 Optimization - Hill Climbing Mutation Algorithm -- 7 Optimization Results and Discussion -- 7.1

Initial Model and Inputs of the Design -- 7.2 Results -- 7.3 Discussion -- 8 Conclusions -- References -- Development of a Database to Simulate and Adapt Compliant Mechanisms to a Given Characteristic for Improving Energy Efficiency of a Walking Robot -- 1 Introduction -- 2 Desired Characteristic -- 3 Database Design -- 3.1 Mathematical Model -- 4 Validation -- 5 Choosing a Compliant Mechanism.
6 Discussion and Outlook -- References -- Analytical Characterization of Spatial Compliant Mechanisms Using Beam Theory -- 1 Introduction -- 2 Analytical Model -- 2.1 Mathematical Description of the Deformation State -- 2.2 Solution Process -- 3 Verification and Application -- 4 Conclusions -- References -- Study of Curved Beam Based Displacement Amplifying Compliant Mechanism for Accelerometer Design -- 1 Introduction -- 2 Accelerometer Designs -- 2.1 Conventional Accelerometer -- 2.2 Accelerometer Employing Compliant Mechanism -- 3 Optimization of DaCM -- 4 Accelerometer Using Compliant Mechanism -- 5 Results and Discussion -- 5.1 Modal Frequencies -- 5.2 Cross-Axis Sensitivity -- 5.3 Stress -- 5.4 Non-linearity -- 5.5 Capacitance -- 6 Analysis of Fabrication Induced Variations -- 7 Conclusion -- References -- Model of a Micromechanical Modal-Localized Accelerometer with an Initially Curvedmicrobeam as a Sensitive Element -- 1 Introduction -- 2 Proposed Accelerometer Model -- 3 Mathematical Model -- 3.1 Static Equilibrium Equations -- 3.2 The Equation of Small Oscillations Around Static Equilibrium -- 4 Parameters of the Structure Under Consideration -- 5 Diagrams of Static Equilibrium -- 6 Analysis of Small Oscillations Around Equilibrium Position -- 6.1 Finite-Element Modeling -- 6.2 Dependence of Natural Frequencies on the Parameters of Static Voltage and Axial Force -- 7 Conclusions -- References -- Different Beam Configurations for Compliant Mechanism-Based MEMS Accelerometer -- 1 Introduction -- 2 DaCM in MEMS Accelerometer -- 3 Analytical and Numerical Study -- 4 Results and Discussion -- 4.1 Influence of p on the Characteristics of DaCM -- 4.2 Variation in Keq and Meq Due to Folded Beam Configuration -- 4.3 Characteristics of MEMS Accelerometer Combined with DaCM -- 5 Conclusion -- References.
Design and Analysis of the Two-Level Accelerometer -- 1 Introduction -- 2 Design -- 3 Analysis and Discussions -- 4 Conclusion -- References -- Microchannel Induced Tailoring of Bandwidth of Push-Pull Capacitive MEMS Accelerometer -- 1 Introduction -- 2 Device Structure -- 3 Results and Discussions -- 4 Conclusion -- References -- A Comparison of Ring and Disk Resonator Gyroscopes Based on Their Degenerate Eigenmode Shapes -- 1 Introduction -- 2 Methodology -- 3 Results and Discussions -- 4 Conclusions -- References -- Parametric Tuning of Natural Frequencies of Tuning Fork Gyroscope -- 1 Introduction -- 2 Dual Mass Tuning Fork Gyroscope -- 2.1 Dual Mass TFG with Spring Coupling -- 3 Conclusions -- References -- Design and Analysis of Single Drive Tri-Axis MEMS Gyroscope -- 1 Introduction -- 2 Analytical Studies -- 2.1 Drive Mode -- 2.2 Roll and Pitch Modes -- 2.3 Yaw Mode -- 3 Numerical Studies -- 4 Results and Discussion -- 5 Conclusion -- References -- Analysis of the Equilibrium of a Magnetic Contactless Suspension -- 1 Introduction -- 2 Mathematical Model -- 3 Equilibrium -- 4 Magnetic Spring Constant of the Suspension -- 5 Conclusion -- References -- Frequency Analysis of Microbeam with Axial Pretension Using MSGT -- 1 Introduction -- 2 Mathematical Formulation -- 2.1 Modified Strain Gradient Theory -- 2.2 Surface Elasticity -- 2.3 Governing Equation of Motion -- 3 Solution Procedure -- 3.1 Analytical Solution -- 3.2 Differential Quadrature Method (DQM) -- 4 Results and Discussion -- 4.1 Strain Gradient Effects -- 4.2 Strain Gradient with Surface Elasticity

-- 5 Conclusions -- References -- Nonlocal Nonlinear Analysis of Functionally Graded Nano Plates Used in MEMs Devices -- 1 Introduction -- 2 Eringens Nonlocal Model -- 3 Equivalent Properties of Functionally Graded Materials -- 4 Governing Equations -- 5 Numerical Examples -- 6 Conclusions.
References -- Finite Element Analysis of Squeezed Film Damping on Trapezoidal Microcantilever Resonators at Different Pressure Levels -- 1 Introduction -- 2 Squeezed Film Damping -- 3 FEM Analysis -- 3.1 Verification of FEM Model -- 4 Results and Discussions -- 5 Conclusions -- References -- Two-Dimensional Hydrodynamic Forces in an Array of Shape-Morphed Cantilever Beams -- 1 Introduction -- 2 Governing Equations -- 2.1 Transverse Velocity of a Shape-Morphed Cantilevers -- 2.2 Non-dimensionalization and Numerical Procedure -- 3 Results and Discussions -- 3.1 Hydrodynamic Force -- 3.2 Hydrodynamic Coefficient -- 4 Conclusion -- References -- Design and Performance Analysis of TiOx Based MEMS Bolometer Pixel -- 1 Introduction -- 2 Proposed Device Structure -- 3 Results and Discussions -- 4 Conclusions -- References -- FEM Analysis of Split Electrode IDTs Designed Lithium Tantalate-Polyaniline SAW Gas Sensor -- 1 Introduction -- 2 Model Design -- 3 Simulation Methodology -- 4 Results and Discussions -- 5 Conclusions -- References -- Thermal Study of Thin-Film Heater for PCR Reaction-Based Applications -- 1 Introduction -- 2 Thin Film Heater Design -- 2.1 Serpentine Geometry of Heater -- 2.2 Structure Optimization of the Serpentine Heater -- 3 Fabrication of Thin Film Heater -- 4 Thermal Study of Thin Film Heater -- 5 Conclusions -- References -- Etching Characteristics of Si{110} in NaOH Based Solution -- 1 Introduction -- 2 Experimental Details -- 3 Results -- 4 Conclusions -- References -- Effect of IPA on Micromachining Characteristics of Silicon in KOH-Based Solution -- 1 Introduction -- 2 Experimental Details -- 3 Results and Discussion -- 3.1 Etch Rate -- 3.2 Etched Surface Roughness and Morphology -- 3.3 Undercutting -- 4 Conclusions -- References -- Deep Grooves in Borofloat Glass by Wet Bulk Micromachining -- 1 Introduction.
2 Experimental Details -- 3 Results and Discussion -- 4 Conclusions -- References -- Micro-piezo Actuator for Cell Lysis -- 1 Introduction -- 2 Methodology -- 2.1 Sample Preparation -- 2.2 IDT Fabrication -- 2.3 PDMS Microchannel Fabrication -- 2.4 Device Setup and Operation -- 3 Results and Discussion -- References -- Wax-Printed Microfluidic Paper Analytical Device for Viscosity-Based Biosensing in a 3D Printed Image Analysis Platform -- 1 Introduction -- 2 Materials and Methods -- 2.1 Materials -- 2.2 Fabrication of the Microfluidic Wax-based Paper-based Analytical Device (-PAD) -- 3 Experimentation -- 3.1 Integrated Image Processing Platform with Raspberry Pie Module and µPAD -- 3.2 Estimation of Viscosity -- 4 Result and Discussion -- 4.1 Denaturation of BSA -- 4.2 Denaturation of Lysozymes -- 5 Conclusion -- References -- Detection of Volatile Organic Compounds Using Solution Processed Organic Field-Effect Transistors -- 1 Introduction -- 2 Materials and Methods -- 2.1 Model and Simulation Methodolgy -- 3 Results and Discussion -- 3.1 Modelling of Vapour Interactions with the Organic Semiconductor -- 4 Conclusions -- References -- Thickness Dependent Chlorpyrifos Sensing Behavior of Silver Doped ZnO Nanowires -- 1 Introduction -- 2 Experimental Work -- 3 Results and Discussion -- 4 Conclusion -- References -- Investigation of AuCl3 Doped MoS2 Based IR Detector with the Variation of Annealing Temperature -- 1 Introduction -- 2 Experimental Work -- 3 Results and Discussion -- 4 Conclusion -- References -- Investigation of Structural and Electrical Properties of Ta2O5 Thin Films

with Sputtering Parameters for Microelectronic Applications -- 1 Introduction -- 2 Experimental Details -- 3 Results and Discussion -- 4 Conclusion -- References.

Optimization of Controllable Pulsed LASER Deposition Parameters for the Fabrication of Lead Free Ba(Zr0.15Ti0.85)O3 Thin Films.